

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:)
Koichiro TANAKA) Confirmation No. 9528
Application No. 10/769,820) Examiner: Samuel M. Heinrich
Filed: February 3, 2004) Group Art Unit: 3742
For: LASER IRRADIATION STAGE, LASER) January 27, 2009
IRRADIATION OPTICAL SYSTEM, LASER)
IRRADIATION APPARATUS, LASER)
IRRADIATION METHOD, AND METHOD OF)
MANUFACTURING A SEMICONDUCTOR)
DEVICE)

MAIL STOP AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

AMENDMENT UNDER 37 C.F.R. § 1.111

In response to the Final Office Action mailed October 28, 2008, please amend the above-captioned application, as follows:

Amendments to the Claims are reflected in the listing of claims in this paper.

Remarks follow the amendment section of this paper.